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Calibration and Standardization Issues in Scanning Force and Interfacial Force Microscopy

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Generalized view of a scanning probe microscope (SPM)



Quantifiable Parameters in SPM

Instrumental

- 1. Motion in X, Y, Z
- 2. Tip Shape
- 3. Interaction parameter (current, potential, force, etc.)

<u>Data</u>

- 1. Roughness
- 2. Indent shape/volume

Scanner parameters that need to be characterized



C_i – piezoelectric response [nm/V]

Crosstalk - rotational (r), angular (θ) and translational (t).

Closed loop scanners correct largely for these.

Verein Deutscher Ingenieure, VDI/VDE 2656, Draft 1, Dec. 2006

X,Y Calibration Standards

1D grating: 3 images (MBE structures, 30 nm pitch)



Example: Z Calibration Standards

10.0 µm

NIST

NIST instrument

Step height determination for Reference Standards (NIST Reports 821/261141-99 and 821/265166-01)

From ISO 5436-1:2000 – Profile measurement



Example: AFM Tip Shape

SEM imaging for tip radius estimation



best fit polynomial



Blind Reconstruction



tip image







What information can SFMs provide?

Topography – cantilever bending vs. XY

Adhesion – cantilever bending

Friction – cantilever twisting

Nanomechanical properties (e.g., elastic modulus) – nanoindentation

Interfacial Force Microscopy (IFM)

Typical cantilever behaviour



AFM is excellent for imaging but has severe limitations as an indenting tool







Indentation Experiments



IFM Nano-indentation on Kevlar





Graham, J.F., McCague, C., Warren, O.L., Norton, P.R., *Polymer* 41, 4761 (2001)



What needs to be calibrated for nanoindentation?

- 1. Tip shape/size.
- 2. Force
- 3. XY

IFM tip shape/size

SEM Tip Image

Fit shape





Etched W tips E \approx 400 GPa Parabolas. R \approx 100 nm

Can be: passivated, derivatized



Oliver, W. C.; Pharr, G. M. *Journal of Materials Research* 1992, 7, 1564.

Standard Method

Indent a standard with known Young's modulus and hardness at varying loads and estimate the cross sectional area from:

$$A = \pi \left[S \frac{1}{2\beta E^*} \right]^2$$

$$C_{t} = \frac{1}{S} + C_{i} = \frac{1}{2\beta E^{*}} \sqrt{\frac{\pi}{A}} + C_{i}$$

The instrument compliance is assumed to linearly combine with the tip-sample compliance

Problem!

Parameters become interdependent which forces iteration to ensure self-consistency

New Method (D. Munoz-Paniagua)

Acquire high resolution SPM images of the tip.

Statistically process them to determine the tip shape, radius of curvature and the transition point between a hemispherical cap and Berkovitch shape.

Use this independently determined Shape Area Function to determine the instrumental compliance.

- A set of different sized tip scans at maximum resolution was generated
- Multiple scan with varying scan directions to check for artefacts
- Saturate height scale and tilt image to ensure on-axis view



Take slices at known intervals from the apex and calculate their area

Plot these areas vs. the distance traveled from the apex and fit. A weighting factor of Y^{-2} boosts the importance of data near the apex in numerical fitting



Comparison

Fused quartz sample provided as a standard by Hysitron:

E* = 69.6 GPa, H = 9.6 GPa

Indentation based approach ($Ci = 3.2 \pm 0.1 \text{ nm/mN}$):

underestimates E* by 1.6% and overestimates H by 9.6%

<u>Scan based approach</u> ($Ci = 4.9 \pm 0.2 \text{ nm/mN}$):

underestimates E* by 0.4% and overestimates H by 2.5%

Effect of shape area function determination on instrumental errors in nano-indentation experiments (submitted Rev. Sci. Inst.)







What needs to be done for high quality quantitative measurements with IFM?

1. Shape/size characterization of etched W tips

Example: widely spaced, sharp, high, vertical objects.

2. Force calibration (especially at lower forces)









X-Y Calibration

Z Calibration







Effect of shape area function determination on instrumental errors in nano-indentation experiments (for submission to Rev.Sci. Instrum.)



<u>Overview</u>

This project will construct a research tool that will quantitatively probe adhesive and mechanical properties of materials on the nanoscale.

The interfacial force microscope (IFM) technology is being transferred from the group of Professor Peter Norton, Department of Chemistry, University of Western Ontario.

We are constructing an IFM in order to implement the tool as a general usage device for routine and custom experimentation for the NINT and University of Alberta (U of A) research community.

AFM vs. IFM Force Detection



AFM is excellent for imaging but has severe limitations as an indenting tool

Progress

- 1. Construction began in January 2006 at UWO base and scanner assembly
- 2. Main components machined and assembled by July 2006.
- 3. DMP relocated to NINT August 2006
- 4. Final components now finished (heat shielding)
- 5. DMP presently in London, ON doing final assembly and testing
- 6. Commercial SPM controller, fiber interferometer, borescope and temperature controller ordered via Capital funding.

IFM system being built for NINT

-Encoded X, Y, Z sample stage can find a volume of ~10 zL inside a 4mL envelope (formerly stepper motors)

-Updated sample heating/cooling and sensor shielding for operation ~200 to 600K

-Pressure gauge in chamber (chamber is designed to go down to roughing vacuum)

-Top viewing capabilities using a fibre inspection camera

-Isolated ground inputs for additional signals

-Interchangeable scanners

Photos from December 5, 2006 (UWO)



Delivered and Installed at NINT: February 2007

Operational: March 2007

Coupling laser interferometry to IFM:

Detection of force-compensated probes



Comb Drive Sensors: pN Sensitivity

With Walied Moussa (Mech Eng)

- integrated assembly
- very small footprint
- displacement sensed optically
- displacement linear with voltage
- balanced sensor design
- pico Newton sensitivity
- retains force compensation



 $x = \frac{1}{k} \mathcal{E}_0 n \frac{h}{g} V_0^2$

- where : k = spring constant n = number of comb fingers h = height of comb finger g = gap between comb fingers $\mathbf{V}_0 = applied voltage$
- For linear motion use a push pull mode with two opposite actuators A and B so that

$$x = \frac{1}{k} \varepsilon_0 n \frac{h}{g} \left[\left(V_A - V_0 \right)^2 - \left(V_B - V_0 \right)^2 \right]$$

When $V_{A} = -V_{B}$ all quadratic terms cancel and

$$x = \frac{1}{k} \mathcal{E}_0 n \frac{h}{g} 2 V_A V_0$$

Nanoscale Graphitic Carbon Structures and Devices Rongbing Du and Mark T. McDermott



-500 +

-0.2

-0.1

Pyrolyzed SU-8

1000 1100 1200 1300 1400 1500 1600 1700 1800 Raman Shift (cm⁻¹)

Potential (V vs. Ag/AgCl)

0.2

0.3

0.4

0.5

0.6

0.1

0.0

Sapphire: A viable alternative?





Harder Tips:

Diamond can be used but it is expensive and brittle

